

SRM Institute of Science and Technology College of Engineering and Technology

SET A

DEPARTMENT OF ECE

SRM Nagar, Kattankulathur – 603203, Chengalpattu District, Tamilnadu

Academic Year: 2022-2023 (EVEN)

Test: CLAT- 3

Course Code & Title: 18ECC206J - VLSI Design

Year & Sem: III & VI

Date: 02.05.2023

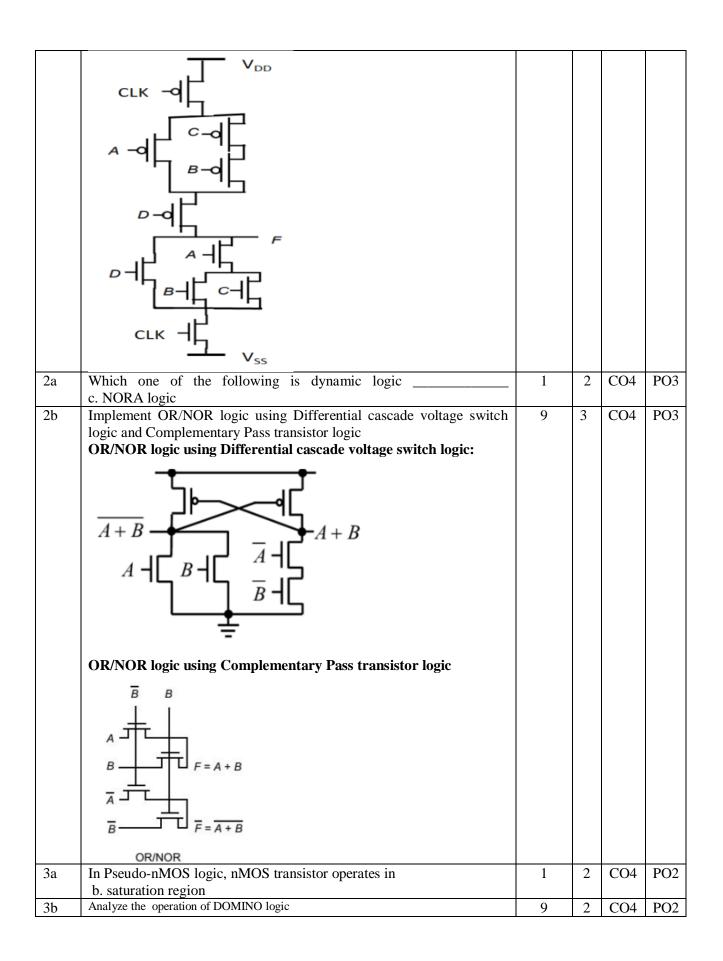
Time: 8.00 to 9.40 AM

Max. Marks: 50

Course Articulation Matrix:

18ECC206J - VLSI Design				Program Learning Outcomes (POs)												
			Graduate Attributes									PSO				
S. No.	Course Outcomes (COs)	1	2	3	4	5	6	7	8	9	10	11	12	1	2	3
1	Design and implement digital circuits using Verilog HDL to simulate and verify the designs.	-	3	3	-	3	-	-	-	-	-	-	-	2	-	-
2	Design general VLSI system components, adder cells and multipliers to address the design of data path subsystem.	-	3	3	-	3	-	-	-	-	-	-	-	2	-	-
3	Examine the characteristics of MOS transistors	3	2	-	-	-	-	-	-	-	-	-	-	2	-	-
4	Analyze CMOS inverter and other complex logic gates designed using different logic styles	-	2	2	-	-	-	-	-	-	-	-	-	2	-	-
5	Explain how the transistors are built, and understand the physical implementation of circuits.	-	1	1	-	-	-	-	-	-	-	-	-	2	-	-

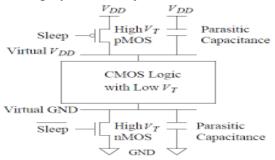
	Answer any 5 Five Questions							
Q.No	Question	Marks	BL	СО	РО			
1a	If nMOS-transistor conducts and has large voltage between source and drain, then it is said to be inregion			CO4	PO2			
	b) saturation							
1b	i) Implement the Boolean function $\bar{F} = (a.b.c) + d$ using complementary CMOS Logic	4	4	CO4	PO3			
	ii) Design the Boolean function $\bar{F} = \overline{(d+a.(b+c))}$ using dynamic CMOS logic	5	4	CO4	PO3			



	precharge: high				
	evaluate: falls (maybe)				
	nfets buffer might				
	be needed				
	in any case				
	CLK -6 - CLK -6 for high fan-out				
	'\ \ \ \ \ \ \ \ \ \ \ \ \ \ \ \ \ \ \				
	A Programment A				
	evaluate rises (maybe) V				
	When CLK is low, dynamic node is pre-charged high and buffer inverter				
	output is low.				
	NFETs in the next logic block will be off.				
	When CLK goes high, dynamic node is conditionally discharged and the				
	buffer output will conditionally go high.				
	Since discharge can only happen once, buffer output can only make one low-				
	to-high transition.				
	• When domino gates are cascaded, as each gate "evaluates", if its output rises,				
	it will trigger the evaluation of the next stage, and so on like a line of				
	dominos falling.				
	• Like dominos, once the internal node in a gate "falls", it stays "fallen" until it				
	is "picked up" by the pre-charge phase of the next cycle.				
	Thus many gates may evaluate in one eval cycle.				
	_ / ' '				
	CLK — L				
	nfetø				
	. W-1-PET "1" 1 1 11 1 1				
	Weak pFET "keeper" keeps dynamic node pulled high during evaluate phase				
	if it's not being pulled down through nfets => gate is static in both				
	clock phases.				
	"latching" pFET acts like keeper above unless dynamic node gets pulled				
	down during evaluate phase. When buffer output goes high it switches				
	keeper off saving static power. Good for leakage current problems				
	Note that you can put an even number of static gates after the inverter and				
	before the next domino gate.				
	Disadvantages:				
	"charge sharing" between nodes in the pulldown network and the dynamic				
	node can unintentionally reduce the voltage of the dynamic node enough to				
	switch output buffer.				
	The addition of the output inverter makes domino gates non-inverting. One				
	can often design around this limitation, but some circuits cannot be				
	implemented solely using domino logic unless both polarities (true and				
	complement) of the inputs are available. If both polarities of inputs are				
	available then we can generate both polarities of internal signals with two				
	domino gates so subsequent stages will have both polarities of their inputs				
	available too.				
4a	Design rules does not specify	1	1	CO5	PO2
	d) colours		1		102
<u> </u>	· ·		_	G G -	DOI
4b	i) Draw 2 -input NOR gate using CMOS layout	4	3	CO5	PO2
	Von				
	"A — ¶ M3 M4 ■ n-well				
	VB —4 €M4				
	Vout				
	VA — M1 VB — M2 GND				
	V _A V _B	~	4	007	DO2
	ii) Implement the boolean expression using stick diagram	5	4	CO5	PO2

	$\overline{\Gamma} = \overline{(\cdot, +1)}$				
	$\bar{F} = \overline{(a+b)c}$				
	GND B A C				
5a	In nMOS fabrication, etching is done usinga. plasma	1	1	CO5	PO2
5b	Illustrate n-well CMOS fabrication process	9	2	CO5	PO2
	Fabrication Process (Theory) - 5 Marks				
	Fabrication Process (Diagram) - 4Marks				
	p substrate				
	NVDIANCE CENTRAL STATE SION SION SION SION SION SION SION SION				
	p substrate				
	SiO,				
	n well				
	Polysilicon Trin gate oxide				
	p auberrate n well				
	n+ n				
	p+ n+ p+ n+ Trick field oxide p substrate n weit				
6a	Silicon oxide is patterned on a substrate using: b) Photolithography	1	1	CO5	PO2
6b	Discuss how enhancement in CMOS technology can be achieved using	9	3	CO5	PO2
	Multiple threshold voltage and high k dielectric				
	 CMOS Process Enhancements: For real time Analog, Digital or RF CMOS integrated circuits along with 				
	transistors, other elements such as interconnects, resistors, capacitors are to				
	be integrated on chip.In order to achieve this, enhancements in CMOS process technology is				
	required.				
	The main goals of adding CMOS enhancements are • To provide on chip capacitors for analog circuits.				
	 To provide on chip resistors. 				
	 To provide routing of interconnects Multi-threshold CMOS (MTCMOS) is a variation of CMOS chip technology which 				
	has transistors with multiple threshold voltages (V_{th}) in order to optimize delay or				
	 Low V_{th} devices switch faster, and are therefore useful on critical delay paths 				
	to minimize clock periods.				

- The penalty is that low V_{th} devices have substantially higher static leakage power.
- High V_{th} devices are used on non-critical paths to reduce static leakage power without incurring a delay penalty. Typical high V_{th} devices reduce static leakage by 10 times compared with low V_{th} devices.



- One method of creating devices with multiple threshold voltages is to apply different bias voltages (V_b) to the base or bulk terminal of the transistors.
- Other methods involve adjusting the gate oxide thickness, gate oxide dielectric constant (material type), or dopant concentration in the channel region beneath the gate oxide.
- The most common implementation of MTCMOS for reducing power makes use of sleep transistors.
- Logic is supplied by a virtual power rail.
- Low V_{th} devices are used in the logic where fast switching speed is important.
- \bullet High V_{th} devices connecting the power rails and virtual power rails are turned on in active mode, off in sleep mode.
- High V_{th} devices are used as sleep transistors to reduce static leakage power.



High k-dielectric

- The dielectric constant k, is a parameter defining ability of material to store charge.
- In Si technology the reference value of k of silicon di-oxide, SiO₂, which is 3.9.
- Dielectrics featuring k > 3.9 are referred to as "high"-k dielectric while dielectric featuring k<3.9 are defined as "low"-k dielectrics.
- In cutting edge silicon nano-electronics both high- and low-k dielectrics are needed to implement fully functional very high-density integrated circuit, although, for drastically different reasons.

Need for high-k dielectric:

- Silicon di-oxide (SiO₂) has been used as a gate oxide material for decades.
- As transistors have decreased in size, the thickness of the silicon dioxide gate dielectric has steadily decreased to increase the gate capacitance and thereby drive current, raising device performance.
- As the thickness scales below 2 nm, leakage currents due to tunneling increase drastically, leading to high power consumption and reduced device reliability.
- Replacing the silicon dioxide gate dielectric with a high-k material allows increased gate capacitance without the associated leakage effects.
- In digital circuits, insulating dielectrics separate the conducting parts (wire interconnects and transistors) from one another.
- As components have scaled and transistors are closer together, the insulating dielectrics have thinned to the point where charge build-up and crosstalk adversely affect the performance of the device.
- Replacing the silicon di-oxide with a low-k dielectric of the same thickness reduces parasitic capacitance, enabling faster switching speeds and lower heat dissipation.

7a	In stick diagram, which color is used for n-diffusion? d) yellow	1	1	CO5	PO2
7b		5	2	CO4	PO2
7b	i) Analyze DC characteristics of CMOS Inverter V_{DD} V_{in} V_{out} As the source of the nMOS transistor is grounded, $V_{gsn} = V_{in}$ and $V_{dsn} = V_{out}$ As the source of the pMOS transistor is tied to V_{DD} , $V_{gsp} = V_{in} - V_{DD}$ and $V_{dsp} = V_{out} - V_{DD}$ $V_{dsn} = -I_{dsp} = V_{dsp}$ $V_{in} = V_{in} + V_{in}$ $V_{in} = V_{in} + V_{in} + V_{in}$ $V_{in} = V_{in} + V_{in} + V_{in} + V_{in}$ $V_{in} = V_{in} + $	5	2	CO4	PO2
	B $V_{tn} \le V_{tn} \cap V_{tn}$ linear saturated $V_{out} = V_{DD}/2$				
	$ \begin{array}{ c c c c c c c c c c c c c c c c c c c$				
	ii) Discuss the interconnect layers involved in CMOS process The interconnect layers involved in process are: (1) Metal interconnect (2) Poly-silicon interconnect (3) Local interconnect (4) The second layer of metal interconnect (Metal 2) is required for digital Integrated circuits. • The connection between first metal layer (Metal 1) and second metal layer (Metal 2) is established with the help of via. • For high speed chips third metal layer (Metal 3) is also required. Poly-silicon Interconnect • Poly-silicon Interconnect layers are used in ICs because of its high melting points as compare to Aluminium (Al). • But the major problem with poly-silicon interconnect is it has high sheet resistance because of this for long distance	4	2	CO5	PO2
	 interconnects this provides significant delay. Local Interconnect If silicide is used as a interconnect layer for connecting different cells—then it is called as local interconnect. The important advantage of local interconnect is it allows direct—connection between poly-silicon and diffusion regions. Due to this metal contacts are eliminated which reduces the chip area. 				